CLAIMS

What is claimed is:

A method of high frequency operation in an integrated circuit, said
 method comprising:

accessing charge stored in a capacitor comprising a plurality of deep n well regions formed in an epitaxy region of said integrated circuit; and coupling said charge to a transistor device of said integrated circuit enabling switching at said high frequency.

- 2. The method of Claim 1 wherein said capacitor further comprises bulk p + material.
- 3. The method of Claim 1 wherein said capacitor further comprises a p

 15 well.
 - 4. The method of Claim 1 wherein said coupling is parasitic.
- The method of Claim 1 wherein said plurality of deep n well regionscomprise substantially parallel stripes.
 - 6. The method of Claim 1 wherein said plurality of deep n well regions comprise a grid.

- 7. The method of Claim 1 wherein said plurality of deep n well regions comprise more than one layer of deep n well.
 - 8. An integrated circuit comprising:

a plurality of transistors having a principal operating voltage;

a deep n well comprising n- material, wherein a portion of said deep n well is coupled to p type material which is coupled to a ground reference of said integrated circuit; and

wherein said deep n well is coupled to said principal operating voltage of said plurality of transistors of said integrated circuit.

- 9. The integrated circuit of Claim 8 wherein said deep n well is substantially surrounded by p type material.
- 15 10. The integrated circuit of Claim 8 comprising a plurality of said deep n wells.
 - 11. The integrated circuit of Claim 8 wherein said deep n well is parasitically coupled to said principal operating voltage.

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- 12. The integrated circuit of Claim 8 wherein said p type material comprises epitaxy.
- 13. The integrated circuit of Claim 8 wherein said p type material25 comprises bulk p material.

- 14. The integrated circuit of Claim 8 wherein said p type material comprises a p well.
- 5 15. The integrated circuit of Claim 14 wherein said p well is at substantially a same depth as said deep n well.
 - 16. An integrated circuit comprising:

 a first deep n well at a first depth; and
 a second deep n well at a second depth.
 - 17. The integrated circuit of Claim 16 wherein said first and said second deep n wells are coupled together.
- 18. The integrated circuit of Claim 16 further comprising a plurality of transistors having a principal operating voltage and wherein said first and said second deep n wells are coupled to said principal operating voltage of said plurality of transistors of said integrated circuit.
- 20 19. The integrated circuit of Claim 16 wherein said first and said second deep n wells are coupled to a ground reference for said integrated circuit.
 - 20. The integrated circuit of Claim 16 wherein said first and said second deep n wells are substantially surrounded by p type material.

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- 21. The integrated circuit of Claim 16 wherein said first and said second deep n wells are formed with the same process mask.
- The integrated circuit of Claim 16 wherein said first and said seconddeep n wells from a power supply decoupling capacitor.
 - 23. The integrated circuit of Claim 16 comprising a p well at substantially said first depth.
- 10 24. An integrated circuit as described in Claim 16 further comprising a deep p well disposed between said first and said second deep n wells.
 - 25. A deep n well capacitor comprising a deep n well region of an integrated circuit, said deep n well coupled to Vdd and ground.

26. The deep n well capacitor of Claim 25 further comprising a plurality

- 27. The deep n well capacitor of Claim 26 wherein said plurality of deep20 n well regions are substantially parallel.
 - 28. The deep n well capacitor of Claim 26 wherein said plurality of deep n well regions comprise deep n well regions at different depths of said integrated circuit.

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of deep n well regions coupled together.

29. The deep n well capacitor of Claim 26 comprising a plurality of p well regions at substantially the same depth as said plurality of deep n well regions and wherein said plurality of p well regions are disposed between said plurality of deep n well regions.

- 30. The deep n well capacitor of Claim 25 wherein said deep n well region is substantially surrounded by p type material.
- 31. The deep n well capacitor of Claim 25 wherein said deep n well region10 is parasitically coupled to said Vdd.